

Sensing Apparatus, System and Method

ABSTRACT

The present invention relates to the field of sensors, sensing
5 apparatus, systems and methods. In particular, the invention relates to
sensors where micro machining is used to manufacture such sensors. In one
aspect the invention provides a micro machined sensing apparatus
comprising:

a microstructure disposed on a substrate having first and second
10 electrode formations, the microstructure comprising a drive structure and a
sense structure, wherein;

the drive structure is adapted to be movably connected to the substrate
and comprises a third electrode formation operatively associated with the first
electrode formation for driving the drive structure, and;

15 the sense structure is adapted to be movably suspended from the
substrate and comprises a fourth electrode formation operatively associated
with the second electrode formation for sensing a resultant motion of the
sense structure and such that the fourth electrode formation is disposed
externally with respect to the drive structure.

20 In one preferred form, the invention relates to an apparatus and
method of detecting a sensed signal in a Micro Electro Mechanical System
(MEMS) for sensing.

Figure 2 accompanies the abstract.